

The Technology of Pure Gas

AMBIENT INLINE PURIFIER 503 PURIFICATION MEDIA SPECIFICATION



0 – 150 slpm Ambient Inline Purifiers. For consistent gas quality and Impurity removal to pptV levels.



MicroTorr Ambient Inline Purifiers:

MicroTorr purifiers are the most complete and reliable solution for Point-of-Use (POU) gas purification. Combining model size with a selection of gas-specific purification materials, MicroTorr purifiers can be tailored to many different customer applications, while maintaining impurity removal to Part-Per-Billion (ppbV) levels or better. Optional valves and a 0.003 micron particle filter are available as well as custom subsystem configurations.

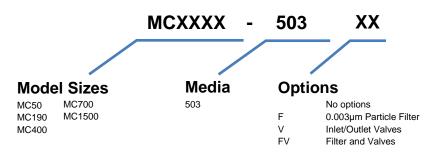
Competitive Advantages and Benefits:

- Reliability: Uncompromised process consistency and yield improvement.
- Performance: State-of-the-art purification technology, low pressure drop, and long lifetimes.
- Regenerability: Most MicroTorr media are factory regenerable, minimizing potentially hazardous waste.
- Quality: 316L stainless steel, Helium leak checked, and analytical testing to part-per-trillion (pptv) levels.
- Support: Lifetime estimation and regeneration service available through SAES Pure Gas Sales Network.

503 Media Purifier Properties				
Gases Purified	H2 with up to 1% O2; O2 with up to 2% H2			
Impurities Removed	H2 in O2 or O2 in H2 < 1 ppm			
Particle Filtration	2 micron or 0.003 micron metal			
Vessel construction	Stainless Steel 316L, electropolished to 10 Ra			
Installation Orientation	Vertically with flow downward. Consult factory for other orientations.			
Leak Rating	1 x 10-9 atm cc/sec of He			
Operating temperature	-20 to 65 °C (-4 to 149°F) Lifetime may be effected at higher temperatures			
Lifetime	Contact SAES Pure Gas for application specific lifetime calculations			
Regenerability	Not Regenerable			
Certification	CE Certified to the Pressure Equipment Directive (PED) Designed in accordance with ASME			

503 Media Purifier Properties

Part Number Configuration:

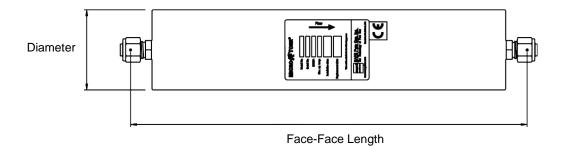




Purifier Sizes

Part Number	Maximum Flow (slpm)	Average Flow (slpm)	Operating Pressure (psig) Must be in gas phase	Inlet Connection	Outlet Connection	Diameter (inches [mm])	Face to Face Length (inches [mm])	Weight (lb. [kg])
Standard M	odels							
MC50-503F	7	1.5	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	5.00 [127.0]	< 0.9 [0.4]
MC190-503F	50	5	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	8.20 [208.3]	< 1.6 [0.7]
MC400-503F	75	9	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	8.20 [208.3]	< 4.9 [2.2]
MC700-503F	100	25	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	10.00 [254.0]	< 7.6 [3.4]
MC1500-503F	150	40	250	1/2" MVCR	1/2" MVCR	3.0 [76.2]	18.20 [462.3]	< 8.0 [3.6]

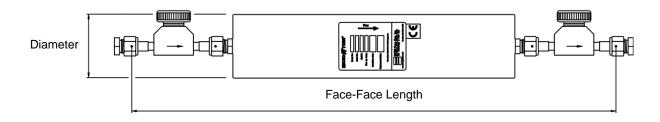
F = 0.003 micron particle filter



Purifier Sizes, with inlet and outlet isolation valves

Part Number	Maximum Flow (slpm)	Average Flow (slpm)	Operating Pressure (psig) Must be in gas phase	Inlet Connection	Outlet Connection	Diameter (inches [mm])	Face to Face Length with valves (inches [mm])	Weight with valves (Ib. [kg])
Standard Mod	els							
MC50-503FV	7	1.5	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	10.60 [269.2]	< 2.9 [1.3]
MC190-503FV	50	5	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	13.80 [350.5]	< 3.7 [1.7]
MC400-503FV	75	9	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	13.80 [350.5]	< 6.8 [3.1]
MC700-503FV	100	25	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	15.60 [396.2]	< 9.6 [4.4]
MC1500-503FV	150	40	250	1/2" FVCR	1/2" FVCR	3.0 [76.2]	28.84 [732.5]	< 12.5 [5.8]

F = 0.003 micron particle filter V = inlet and outlet isolation valves



Bypass and Dual Purifier Manifold Assemblies:

Many configurations are available; please consult the factory for details.

S110-1311	DCN 6389
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Other Purification Media's Available:

Media	Gases Purified	Impurities Removed		
202	CDA, O2, N2, Ar, He, Kr, Ne, Xe, H2, D2, CO2, N2O, NO, CF4	H2O to < 1 ppb		
203	CDA, O2, N2, Ar, He, Kr, Ne, Xe, H2, D2, N2O, NO, CF4	H2O, CO2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppb		
302	HCI, Cl2, B2H6, BCl3, CCIH3, GeCl4, GeH4, H2S, H2Se, HBr, NF3, SiCl4, SiF4, SiH2Cl2, SiHCl3, SO2, CHCIF2, BF3,	H2O to < 1 ppb; Metals < 1 ppb		
403	N2, Ar, He, Kr, Ne, Xe, H2, CDA, O2	Volatile Acids, Organics, Refractory Compounds to <1 ppt; Volatile Bases < 5 ppt, Metals <1 ppb		
404	N2, Ar, He, Kr, Ne, Xe, H2, CDA, O2, CO2, C2H2, C3H6, C2H4, NH3, C2H6, C3H8, C4H10	Organics < 1 pptV, Metals < 1 ppbV		
502	AsH3, PH3	H2O, O2 to < 1 ppb, Metals < 1 ppbV		
503 Covered by this Specification	H2 with up to 1% O2; O2 with up to 2% H2	H2 in O2 or O2 in H2 < 1 ppmV		
602	со	H2O, O2, CO2, Acids, Bases, Organics, Refractory Compounds, Metals < 1 ppbV		
702	NH3, C2H7N, C2H8N2, C2H4, C3H6, CH3SiH3, GeH4, SF6, SiH4, H2/SiH4 mixtures	H2O, O2, CO2, NMHCs, Metals to < 1 ppb		
802	SiH4	H2O, O2, CO, CO2, NMHCs, Sulphur compounds, Metals removal < 1 ppb		
804	C02	H2O, O2, CO, H2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV		
805	CO2	H2O < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV		
902	N2, Ar, He, Kr, Ne, Xe, CH4, C2H6, C3H8, C4H10, SF6, Fluorocarbons	H2O, O2, CO, CO2, H2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV		
904	H2, D2, H2-Inerts Mix	H2O, O2, CO, CO2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV		
906	CDA, O2, N2O	H2O, CO, CO2, NMHC to < 1 ppb, Metals < 1 ppbV		

Purifier Regeneration:

Available from any SAES Pure Gas Regeneration Center.

CE Directive:

All MicroTorr Purifiers meet CE directive requirements and come with the CE Marking.





saes group SAES Pure Gas The Technology of Pure Gas

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SAES Pure Gas is ISO9001 certified ISO 9001:2008



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